

- Laser micromachining system with high power picosecond laser
- High quality laser process with cold ablation
- Highly integrated laser micromachining system designed for R&D and industrial application
- Fully customizable system
- perform (or assist with) process / application development if needed



Pico second laser

High reliable industrial picosecond laser



- Picosecond laser for micromachining
- Wavelength : 532 nm
- Pulse width : < 15 ps
- Average power : 60 W
- High pulse energy : 300 μ J
- Burst mode

*We can offer the best solution

Laser scan

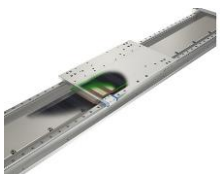
High speed digital galvo-scanner



- Digital galvo-scanner
- Max speed : 25 m/s
- Repeatability : < 2 μ rad
- Tracking error : 0.15 ms

Positioning

High accurate XY linear axes



- High accurate, high speed axes
- Optical glass encoder
- Positioning area : 600 mm \times 400 mm
- Resolution : 0.1 μ m
- Max speed : 700 mm/s
- Low profile stable drive

Beam delivery & vision system

Efficient beam delivery & accurate monitoring



- Beam delivered efficiently
- High accurate vision system
- Fully designed for micromachining

Specification

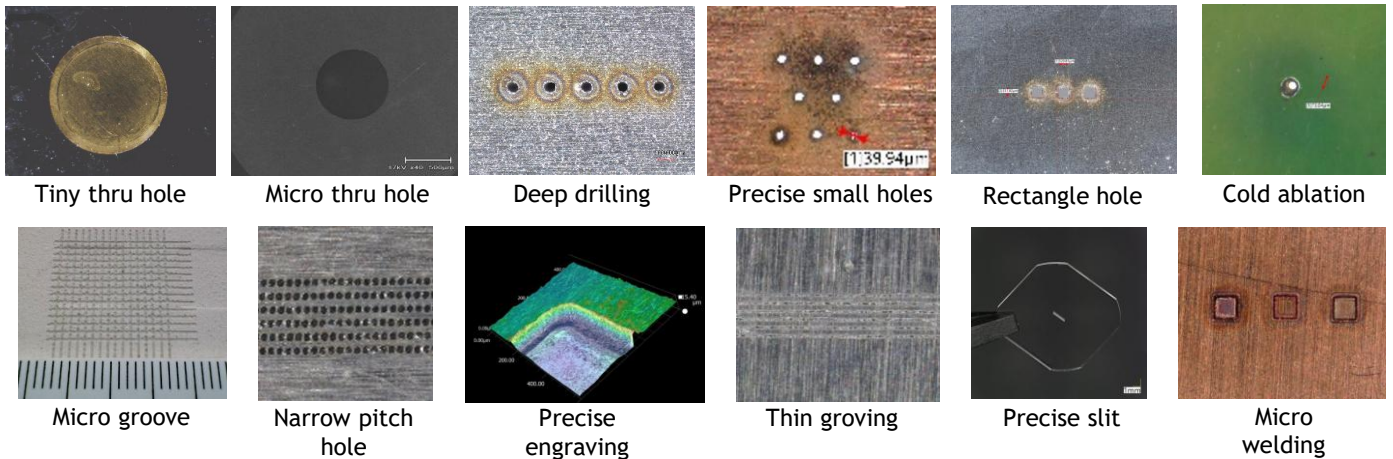
	Item	Value	Remark
Laser	Wavelength	532 nm	
	Average power	60 W	
	Pulse energy	300 μ J	@200kHz burst
	Rep rate	1Hz ~ 2 MHz	
	Pulse width	< 15 ps	
Machining	Beam spot	ϕ 10 μ m	
	Laser scan	Linear stage Galvo scanner	
	Laser scan speed	Linear stage: 700mm/s Galvo-scanner: 25,000mm/s	
	Laser scan area	Linear stage: 600mm x 400mm Galvo-scanner: 40mm x 40mm	

	Item	Value	Remark
Vision system	Area (XY)	600mm x 300mm	
	Area (Z)	150mm	
	Camera	On-axis : 1 Off-axis : 1	
	Resolution	Full HD	
Pointer		Red : 1	
Machining	Beam spot	ϕ 10 μ m	
Dimension		W1200mm x D940mm x H1780mm	
Weight		900kg	

* All device can be castmizable.

Laser micromachining

Examples of laser micromachining



Laser machine

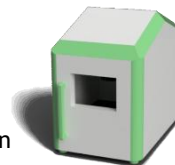
Laser micromachining lineup



- Semiconductor laser
- Wavelength : 450 nm
- Average power : 5 W
- On-axis camera
- Process development



- Semiconductor laser
- Wavelength : 808 nm
- Average power : 20 W
- On-axis camera
- Designed for production



- Nano second laser
- Wavelength : 1064nm
- 50W, 100W
- Galvo-scanner
- Table-top system



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